

DECLARATION OF JOINT INVENTORS FOR PATENT APPLICATION

As the below named inventor, I hereby declare that:

My residence, post office address and citizenship are as stated below next to my name.

I believe I am the original, first and joint inventor of the subject matter which is claimed and for which a patent is sought on the invention entitled: Methods Of Forming Silicon Dioxide Layers, And Methods Of Forming Trench Isolation Regions, the specification of which is attached hereto.

I hereby state that I have reviewed and understand the contents of the above-identified specification, including the claims.

I acknowledge the duty to disclose information known to me to be material to patentability as defined in Title 37, Code of Federal Regulations §1.56.

PRIOR FOREIGN APPLICATIONS:

I hereby state that no applications for foreign patents or inventor's certificates have been filed prior to the date of execution of this declaration.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful

1 false statement may jeopardize the validity of the application or any
2 patent issued therefrom.

3 * * * * *

4 Full name of inventor: **Surjit Sharan**

5 Inventor's Signature: 

6 Date: 7/8/98

7 Residence: **Boise, Idaho**

8 Citizenship: **India**

9 Post Office Address: **5683 S. Alyssum Place, Boise, ID 83706**

10 * * * * *

11 Full name of inventor: **Gurtej S. Sandhu**

12 Inventor's Signature: 

13 Date: 7/6/98

14 Residence: **Boise, Idaho**

15 Citizenship: **United Kingdom**

16 Post Office Address: **2964 E. Parkriver Drive, Boise, ID 83706**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 09/497,080
Priority Filing Date February 2, 2000
Inventor Sujit Sharan
Assignee Micron Technology, Inc.
Priority Group Art Unit 2825
Priority Examiner G. Lee
Attorney's Docket No. MI22-1421
Title: Methods of Forming Silicon Dioxide Layers, and Methods of Forming
Trench Isolation Regions


To: Mail Stop Patent Application
Commissioner for Patents
Art Unit 2825
P.O. Box 1450
Alexandria, VA 22313-1450

From: David G. Latwesen (Tel. 509-624-4276; Fax 509-838-3424)
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ASSOCIATE POWER OF ATTORNEY

Please recognize James E. Lake, whose post office address is 601 W. First Avenue, Suite 1300, Spokane, Washington 99201-3828, as an associate attorney or agent in the above-entitled application.

Date: 3/30/09



David G. Latwesen, Ph.D.
Reg. No. 38,533

EV372452224

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. Unknown
 Filing Date Filed herewith
 Inventor Sujit Sharan et al.
 Assignee Micron Technology, Inc.
 Group Art Unit Unknown
 Examiner Unknown
 Attorney's Docket No. MI22-826
 Title: Methods Of Forming Silicon Dioxide Layers, And Methods Of Forming
 Trench Isolation Regions

**POWER OF ATTORNEY BY ASSIGNEE AND
 CERTIFICATE BY ASSIGNEE UNDER 37 CFR §3.73(b)**

To: Assistant Commissioner for Patents
 Washington, D.C. 20231

Sir:

MICRON TECHNOLOGY, INC., the Assignee of the entire right,
 title and interest in the above-identified patent application by assignment
 attached hereto, hereby appoints the attorneys and agents of the firm
 of WELLS, ST. JOHN, ROBERTS, GREGORY & MATKIN P.S., listed
 as follows:

Richard J. St. John	Reg. No. 19,363
David P. Roberts	Reg. No. 23,032
Randy A. Gregory	Reg. No. 30,386
Mark S. Matkin	Reg. No. 32,268
James L. Price	Reg. No. 27,376
Deepak Malhotra	Reg. No. 33,560
Mark W. Hendricksen	Reg. No. 32,356
David G. Latwesen	Reg. No. 38,533
George G. Grigel	Reg. No. 31,166
Keith D. Grzelak	Reg. No. 37,144
John S. Reid	Reg. No. 36,369
Lance R. Sadler	Reg. No. 38,605
James D. Shaurette	Reg. No. 39,833

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1 and also attorneys Michael L. Lynch (Reg. No. 30,871) and
2 Lia Pappas Dennison (Reg. No. 34,095) of Micron Technology, Inc., as
3 its attorneys with full power of substitution to prosecute this application
4 and transact all business in the Patent and Trademark Office connected
5 therewith.

6 The Assignee certifies that the above-identified Assignment has
7 been reviewed and to the best of Assignee's knowledge and belief, title
8 is in the Assignee.

9 Please direct all correspondence regarding this application to:

10 Wells, St. John, Roberts, Gregory & Matkin P.S.
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16 MICRON TECHNOLOGY, INC.

17 Dated: 7-28-1990

By: [Signature]

18 Name: Michael L. Lynch

Title: Chief Patent Counsel